



上海兆九光电技术有限公司  
Shanghai Mega-9 Optoelectronic Co., Ltd.

## 产品目录(Catalogue)

2013 版

[www.mega-9.com](http://www.mega-9.com)

**Mega-9** is a leading technology manufacturer of advanced narrow bandpass filters and beamsplitter cubes as well as other optical coatings.

Founded in 2006, Mega-9 has developed its own technology in fabricating narrow bandpass filters and various beamsplitters. The center wavelength for bandpass filters varies from 250nm to 1100nm, and the bandwidth varies from 10nm to 50nm according to customer's requirement. The blocking level of OD6 can be achieved and measured.

The application for the filters of Mega-9 includes security monitoring, face recognition, licence plate recognition, photorejuvenation, large screen multi-touch panel, biochemical analysis, distance measurement and other optical instrumentation.

Mega-9 has thousands of coating components in stock for customer's selection. For all stocked filters or beamsplitters, free sample application is available upon request.

地址:上海市松江区施惠路 111 弄 5 号

Add.: No. 5, Lane 111, Shihui Road, Songjiang, Shanghai,  
201600, China

电话(Tel): +86-21-57784688

传真(Fax): +86-21-57784689

Email: [sales@mega-9.com](mailto:sales@mega-9.com)

Homepage: [www.mega-9.com](http://www.mega-9.com)



*Dimension can be customed upon request.*

*High quality, Fast delivery and Economical solution!*

Facility(1500m<sup>2</sup>)



Coaters, 900mm and 1300mm chamber  
IAD E-beam evaporation

Transmission testing for deep OD(up to OD6)



Ultrasonic Cleaning

### BANDPASS FILTER-BP254/12

CWL: 253.7(+3/-1)nm

FWHM: 12+/-2nm

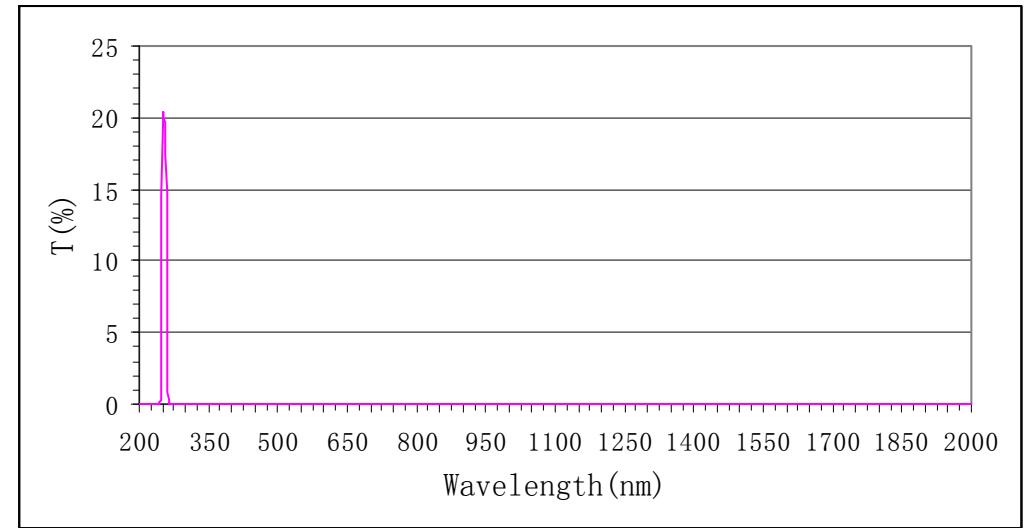
T<sub>peak</sub>: >15%

Blocking: OD4 over 200-3500nm

Dimension: Dia.12.7mm

Thickness: 4.26mm or 6mm

Clear Aperture: >Dia. 8mm



### BANDPASS FILTER-BANDPASS FILTER-BP280/12

CWL: 280(+/-2)nm

FWHM: 12+/-2nm

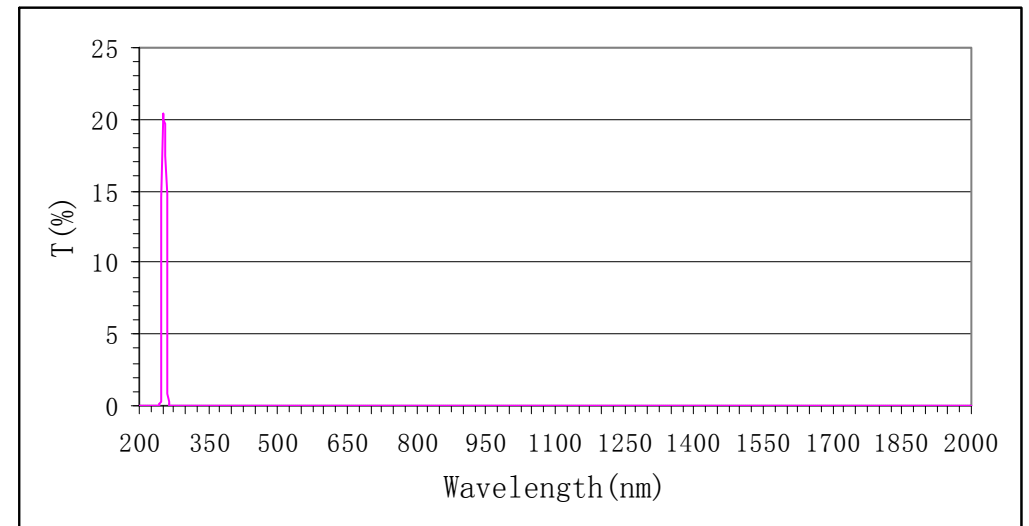
T<sub>peak</sub>: >15%

Blocking: OD4 over 200-3500nm

Dimension: Dia.12.7mm

Thickness: 4.26mm or 6mm

Clear Aperture: >Dia. 8mm



## BANDPASS FILTER-BP365/12

CWL:365(+/-2)nm

FWHM: 12+/-2nm

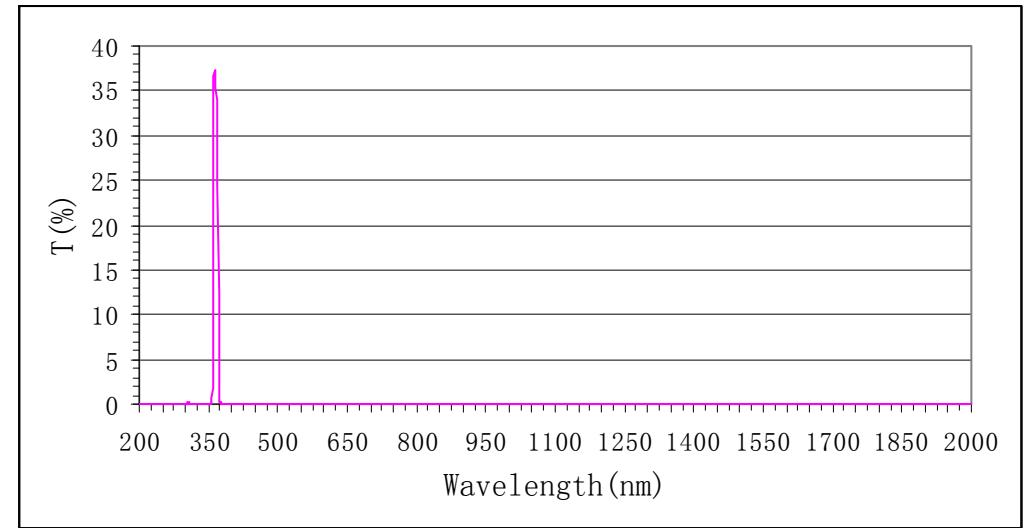
T<sub>peak</sub>:>25%

Blocking: OD4 over 200-3500nm

Dimension: Dia.12.7mm

Thickness: 6mm

Clear Aperture: >Dia. 8mm



## BANDPASS FILTER-BP405/10

CWL:405(+/-2)nm

FWHM: 10+/-2nm

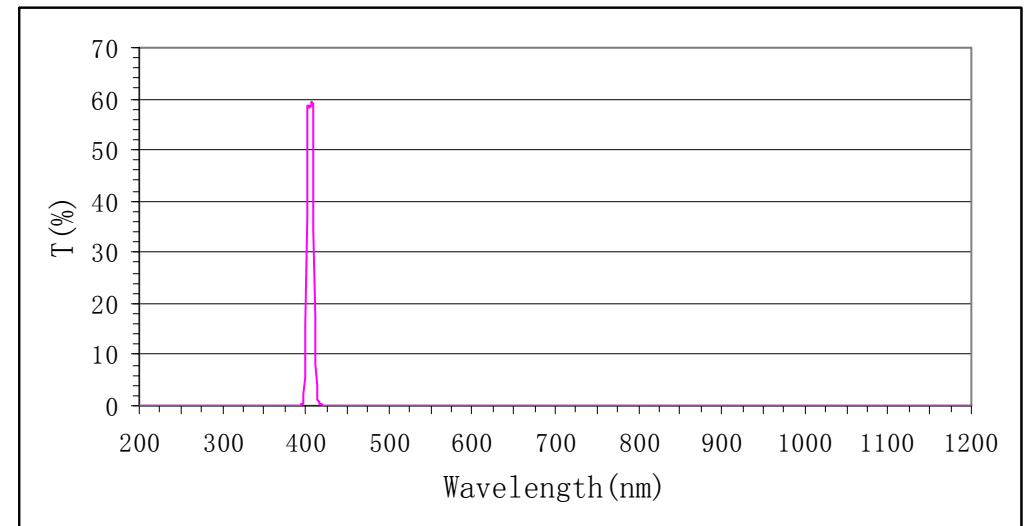
T<sub>peak</sub>:>50%

Blocking: OD5 over 200-1200nm

Dimension: Dia.12.7mm

Thickness: 6mm

Clear Aperture: >Dia. 8mm



## BANDPASS FILTER-BP470/20

CWL:470(+/-3)nm

FWHM: 20+/-5nm

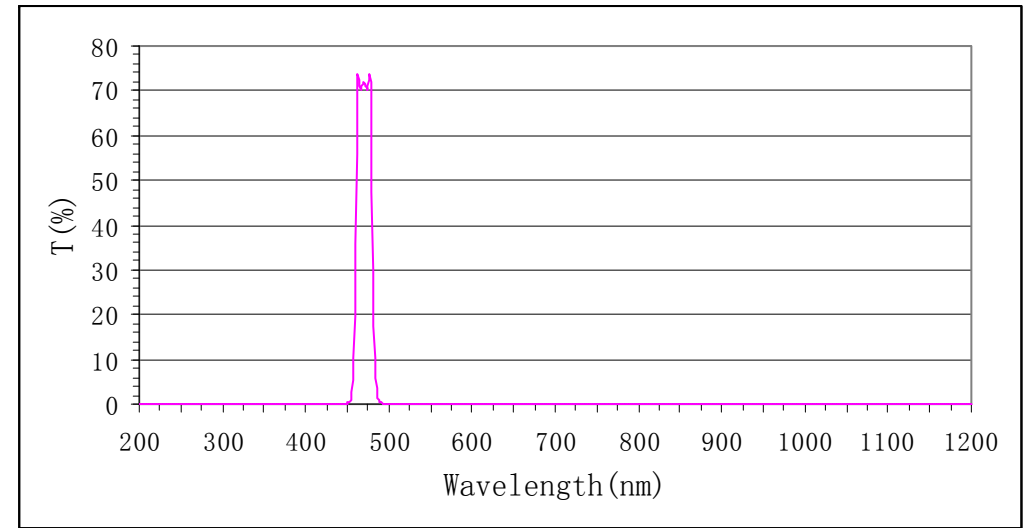
T<sub>peak</sub>:>70%

Blocking: OD4 over 200-1200nm

Dimension: Dia.12.7mm

Thickness: 6mm

Clear Aperture: >Dia. 8mm



## BANDPASS FILTER-BP520/30

CWL:520(+/-5)nm

FWHM: 30+/-5nm

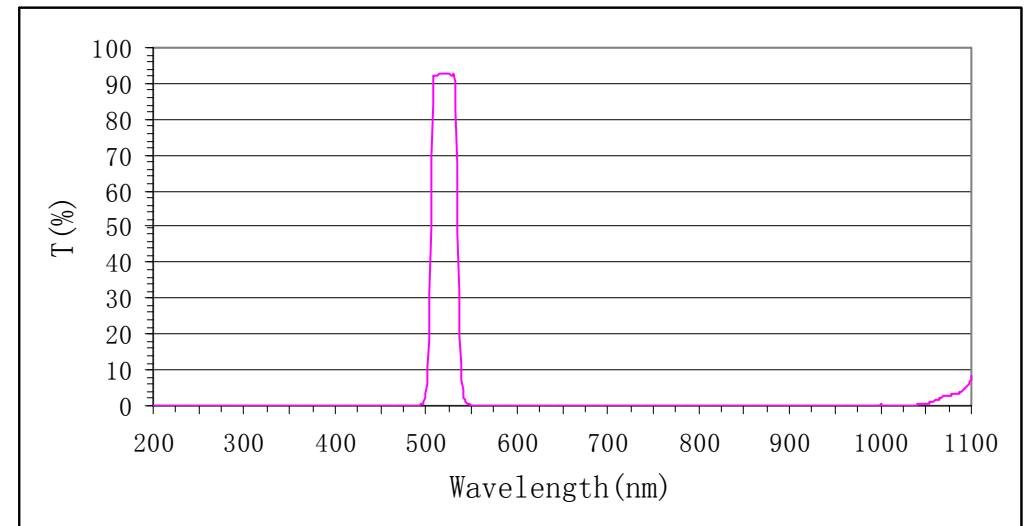
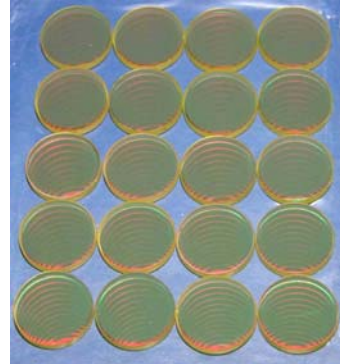
T<sub>peak</sub>:>90%

Blocking: OD3 over 200-1000nm

Dimension: Dia.13.5mm

Thickness: 2mm

Clear Aperture: >Dia. 11mm



## BANDPASS FILTER-BP532/20

CWL:532(+/-3)nm

FWHM: 20+/-5nm

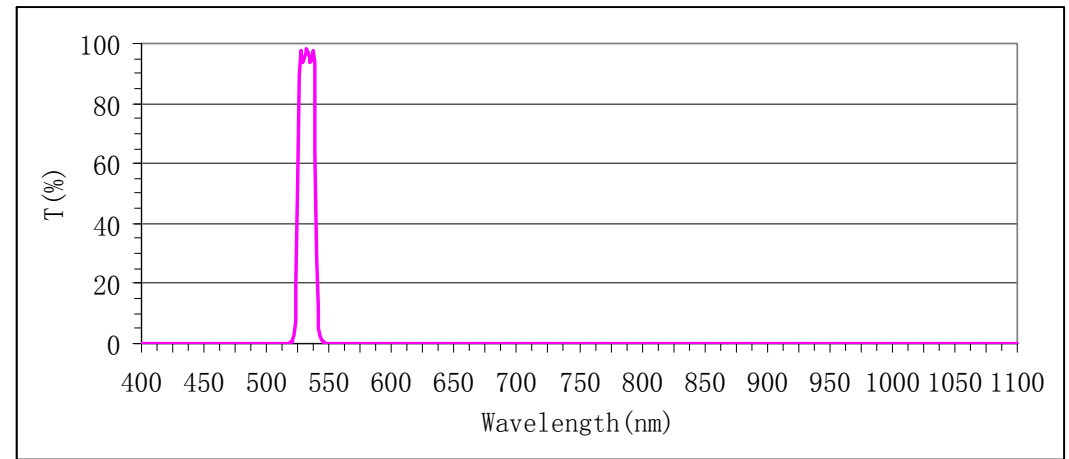
T<sub>peak</sub>:>90%

Blocking: OD4 over 400-1100nm

Dimension: Dia.25mm

Thickness: 1.8mm

Clear Aperture: >Dia. 23mm



## BANDPASS FILTER-BP590/20

CWL:590(+/-3)nm

FWHM: 20+/-5nm

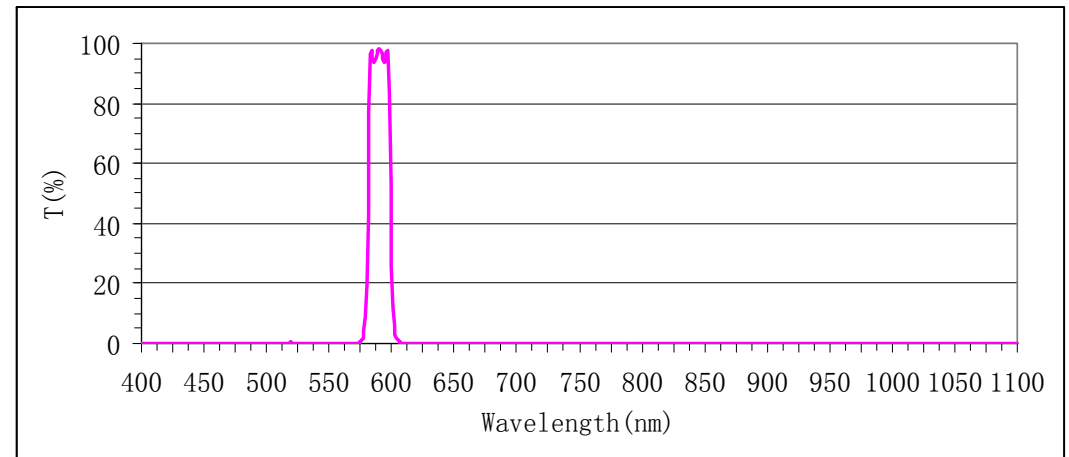
T<sub>peak</sub>:>90%

Blocking: OD4 over 400-1100nm

Dimension: Dia.25mm

Thickness: 1.8mm

Clear Aperture: >Dia. 23mm



## BANDPASS FILTER-BP655/40

CWL:655(+/-5)nm

FWHM: 40+/-5nm

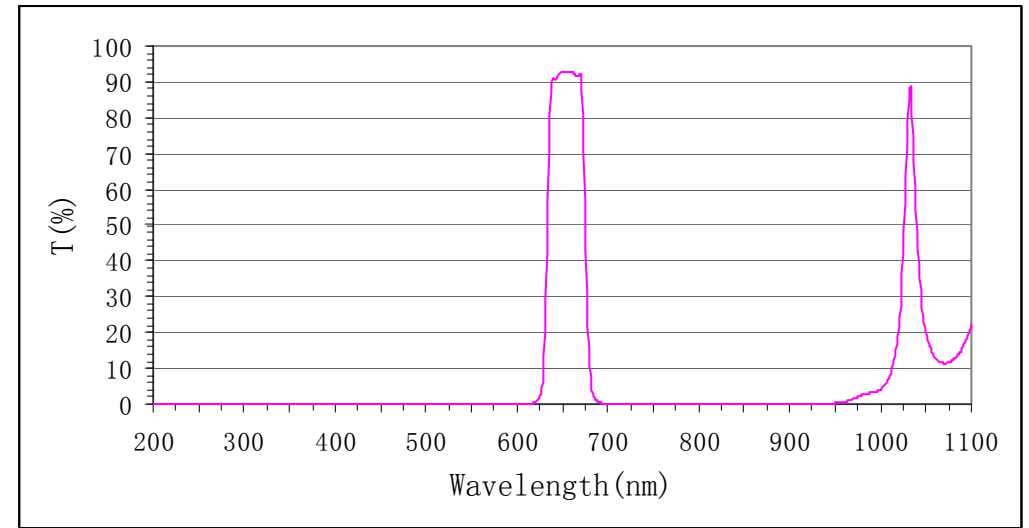
T<sub>peak</sub>:>90%

Blocking: OD3 over 200-950nm

Dimension: Dia.17.3mm

Thickness: 3mm

Clear Aperture: >Dia. 16mm



## BANDPASS FILTER-BP780/30

CWL:780(+/-5)nm

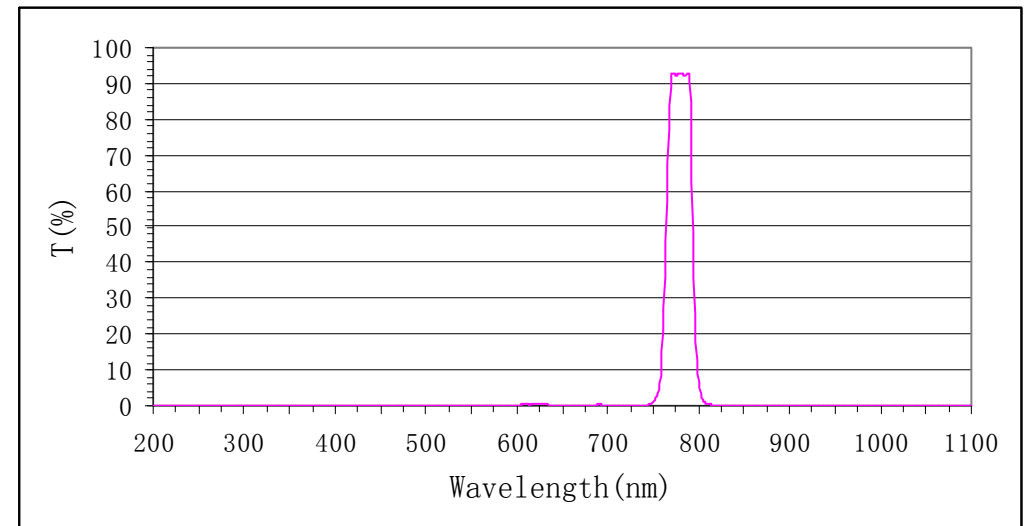
FWHM: 30+/-5nm

T<sub>peak</sub>:>90%

Blocking: T<sub>ave</sub><0.5% over 400-1100nm

Dimension: 8X8, 6X8, 11.4X11.4 or others

Thickness: 0.55





## BANDPASS FILTER-BP808/20

CWL:808(+/-3)nm

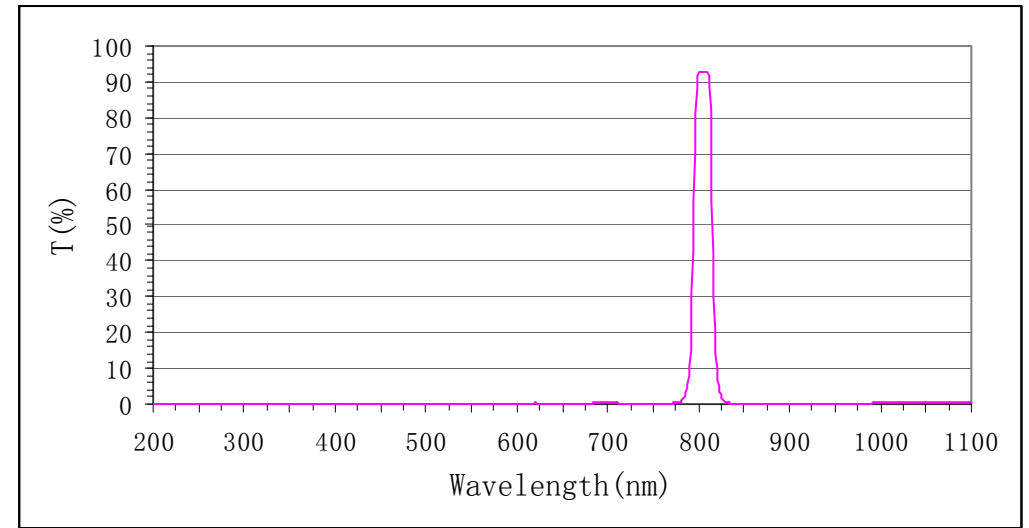
FWHM: 20+/-5nm

T<sub>peak</sub>:>90%

Blocking: T<sub>ave</sub><0.5% over 400-1100nm

Dimension: 8X8, 6X8, 11.4X11.4 or others

Thickness: 0.55



## BANDPASS FILTER-BP808/30

CWL:808(+/-3)nm

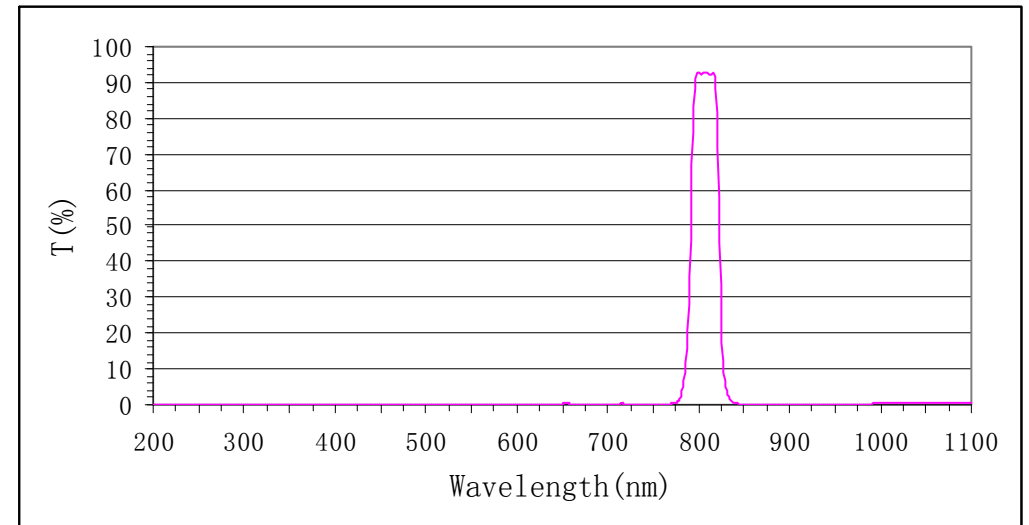
FWHM: 30+/-5nm

T<sub>peak</sub>:>90%

Blocking: T<sub>ave</sub><0.5% over 400-1100nm

Dimension: 8X8, 6X8, 11.4X11.4 or others

Thickness: 0.55





## BANDPASS FILTER-BP850/20

CWL:850(+/-3)nm

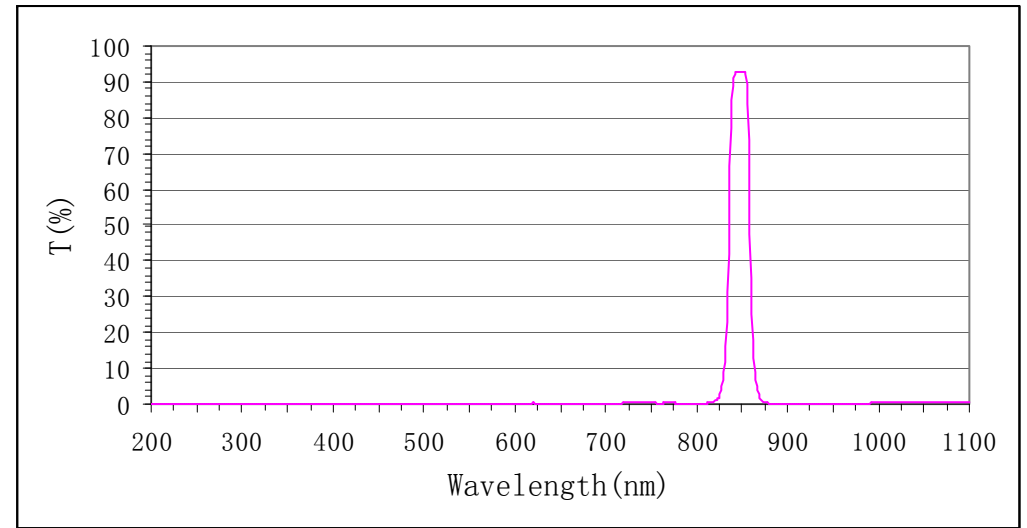
FWHM: 20+/-5nm

T<sub>peak</sub>:>90%

Blocking: T<sub>ave</sub><0.5% over 400-1100nm

Dimension: 8X8, 6X8, 11.4X11.4 or others

Thickness: 0.55



## BANDPASS FILTER-BP850/30

CWL:850(+/-3)nm

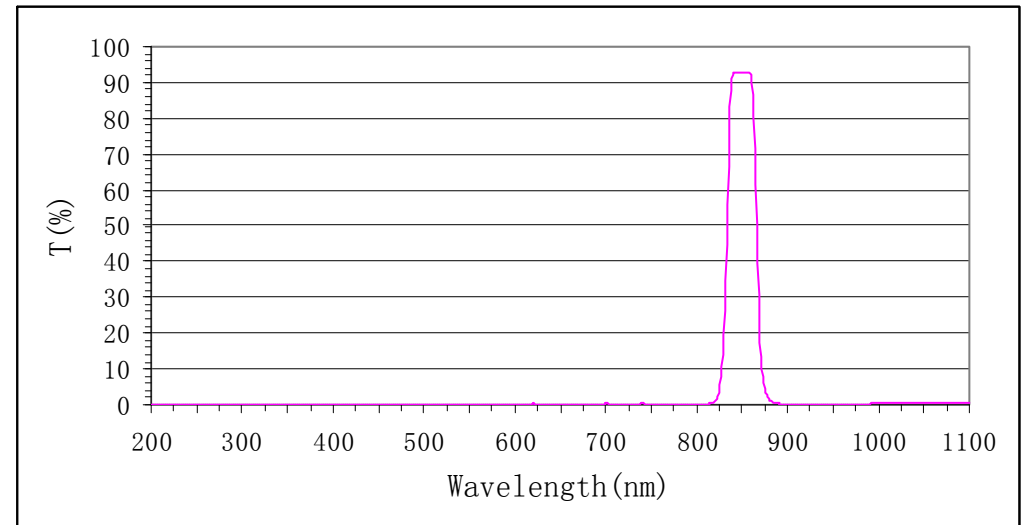
FWHM:30+/-5nm

T<sub>peak</sub>:>90%

Blocking: T<sub>ave</sub><0.5% over 400-1100nm

Dimension: 8X8, 6X8, 11.4X11.4 or others

Thickness: 0.55



## BANDPASS FILTER-BP850/50

CWL:850(+/-5)nm

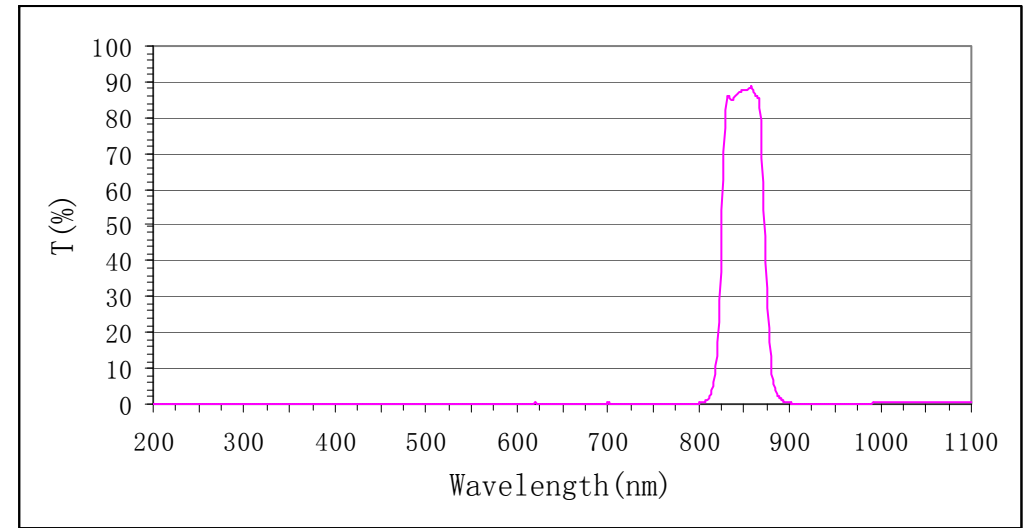
FWHM:50+/-5nm

T<sub>peak</sub>:>90%

Blocking: T<sub>ave</sub><0.5% over 400-1100nm

Dimension: 8X8, 6X8, 11.4X11.4 or others

Thickness: 0.55



## BANDPASS FILTER-BP905/20

CWL:905(+/-5)nm

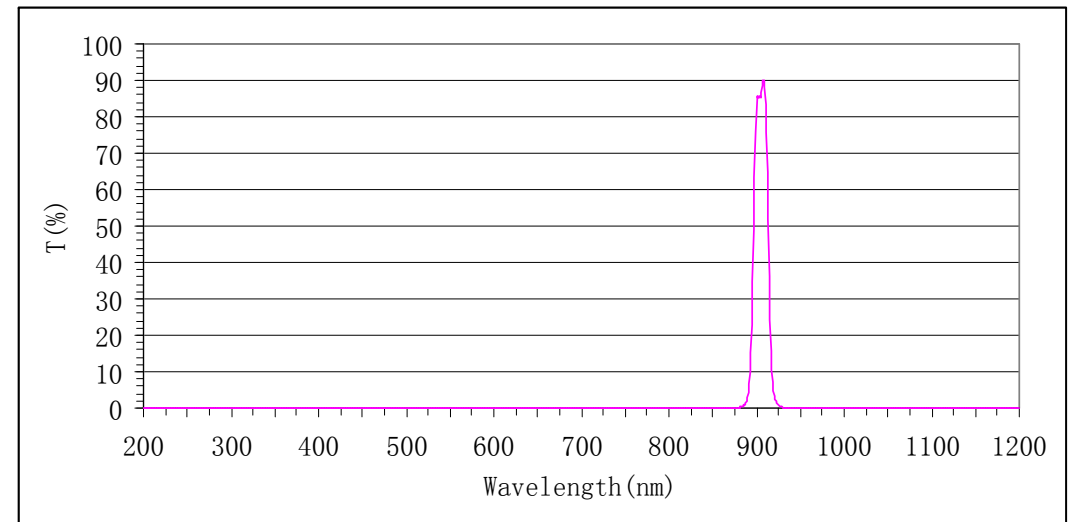
FWHM:20+/-5nm

T<sub>peak</sub>:>80%

Blocking: T<sub>ave</sub><0.01% over 200-1200nm

Dimension:  $\Phi$  12mm

Thickness: 3mm



### BANDPASS FILTER-BP940/30

CWL:940(+/-5)nm

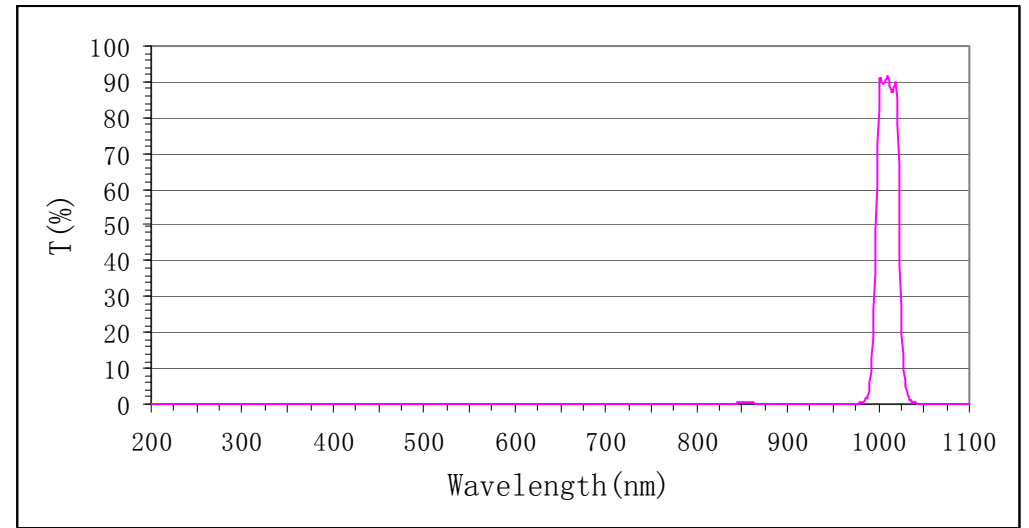
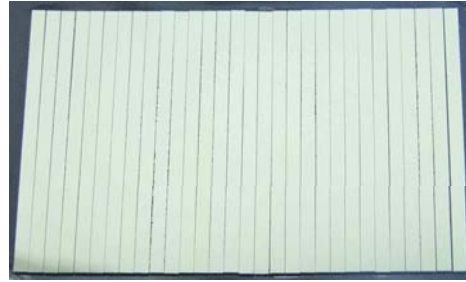
FWHM:30+/-5nm

T<sub>peak</sub>:>90%

Blocking: T<sub>ave</sub><0.5% over 400-1100nm

Dimension: 8X8, 6X8, 11.4X11.4 or others

Thickness: 0.55



### BANDPASS FILTER-BP940/50

CWL:940(+/-5)nm

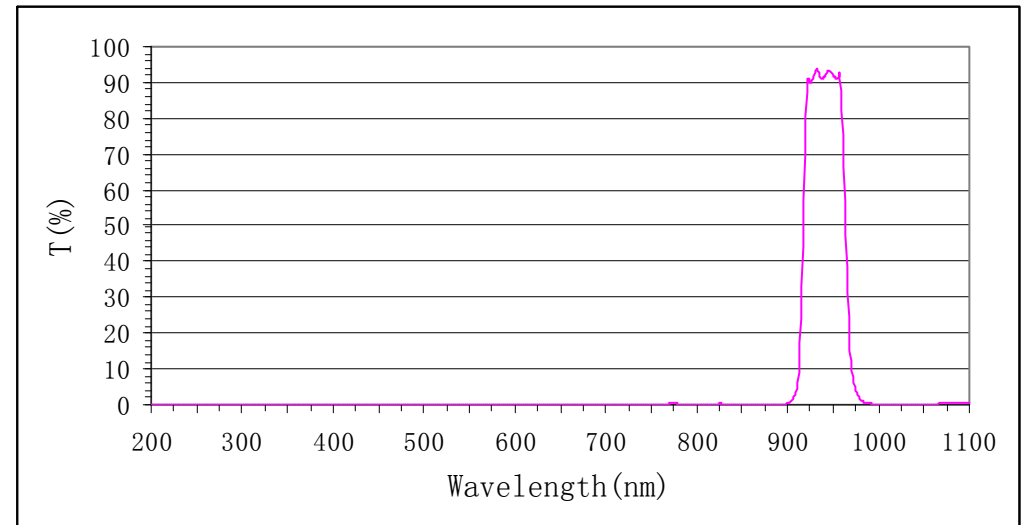
FWHM:50+/-5nm

T<sub>peak</sub>:>90%

Blocking: T<sub>ave</sub><0.5% over 400-1100nm

Dimension: 8X8, 6X8, 11.4X11.4 or others

Thickness: 0.55



## POLARISING BEAM SPLITTER-POLARISING BEAM

### SPLITTER-PBS101

Material: H-ZF3

Dimension: 10X10X10

Surface quality: 60/40

Surface flatness:  $\lambda/10$  at 633nm

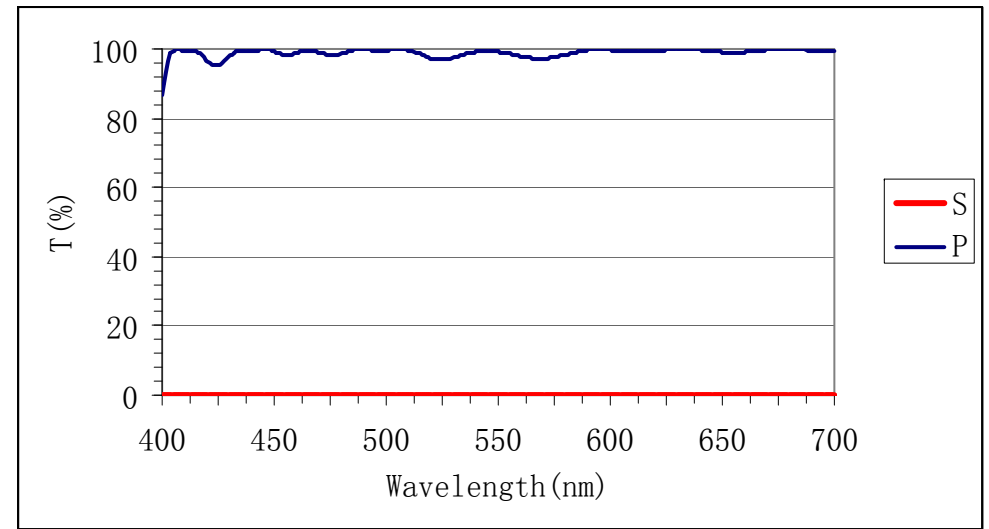
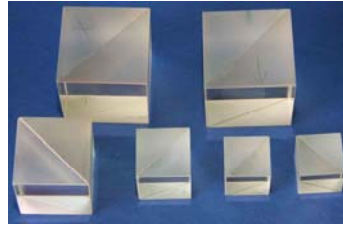
Input/Output surfaces: AR<0.5% over 430~680nm

Hypotenuse: AOI 45 degree,  $T_p > 95\%$  and  $T_s < 0.1\%$  over 430~680nm,

Extinction Ratio greater than 1000

Clear aperture: >85% of dimension

Beam deviation: <5'



## POLARISING BEAM SPLITTER-POLARISING BEAM

### SPLITTER-PBS201

Material: H-ZF3

Dimension: 20X20X20

Surface quality: 60/40

Surface flatness:  $\lambda/10$  at 633nm

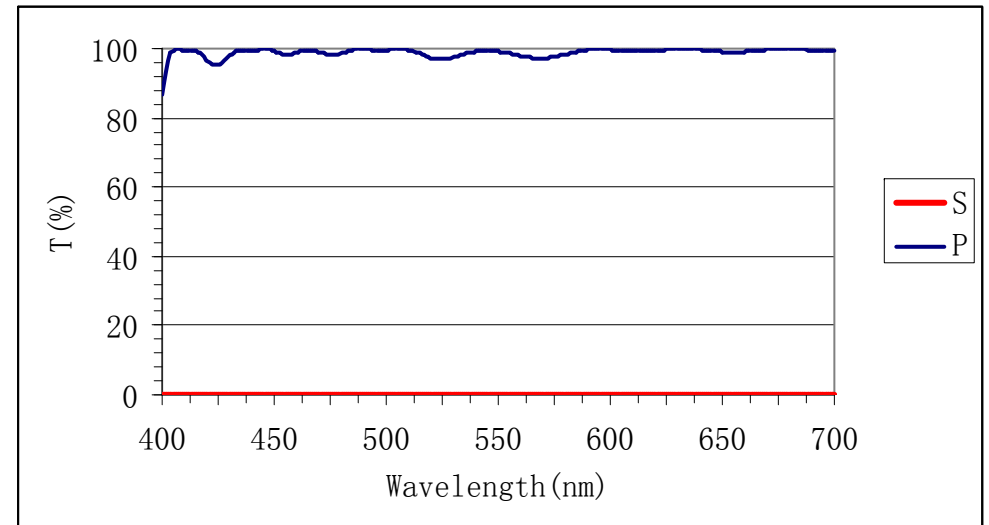
Input/Output surfaces: AR<0.5% over 430~680nm

Hypotenuse: AOI 45 degree,  $T_p > 95\%$  and  $T_s < 0.1\%$  over 430~680nm,

Extinction Ratio greater than 1000

Clear aperture: >85% of dimension

Beam deviation: <5'



### POLARISING BEAM SPLITTER-PBS051

Material: H-ZF3

Dimension: 5X5X5

Surface quality: 60/40

Surface flatness:  $\lambda/10$  at 633nm

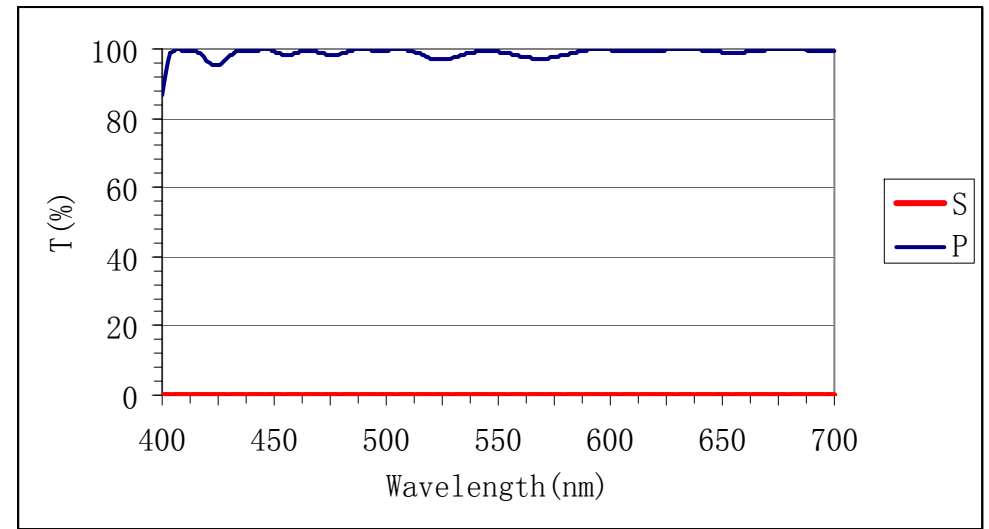
Input/Output surfaces: AR<0.5% over 430~680nm

Hypotenuse: AOI 45 degree,  $T_p > 95\%$  and  $T_s < 0.1\%$  over 430~680nm,

Extinction Ratio greater than 1000

Clear aperture: >85% of dimension

Beam deviation: <5'



### POLARISING BEAM SPLITTER-PBS251

Material: H-ZF3

Dimension: 25.4X25.4X25.4

Surface quality: 60/40

Surface flatness:  $\lambda/10$  at 633nm

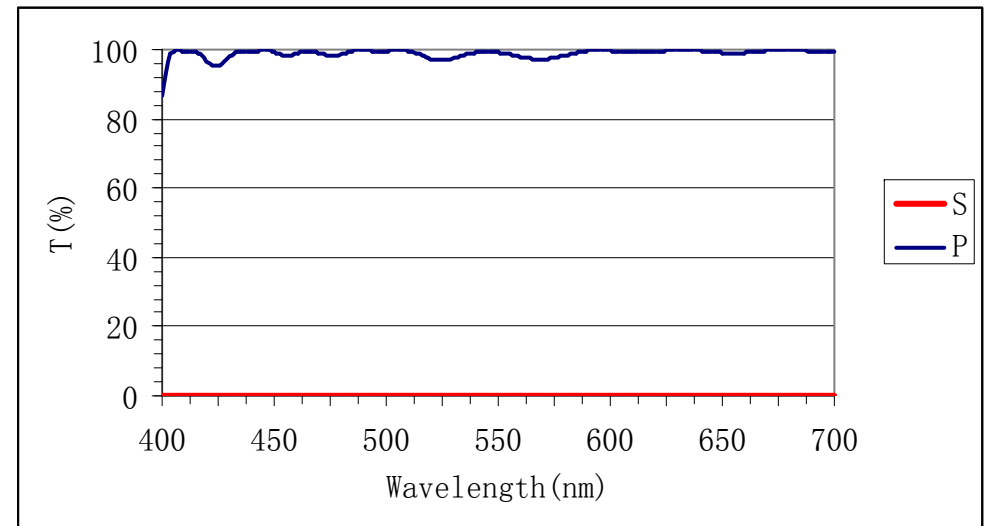
Input/Output surfaces: AR<0.5% over 430~680nm

Hypotenuse: AOI 45 degree,  $T_p > 95\%$  and  $T_s < 0.1\%$  over 430~680nm,

Extinction Ratio greater than 1000

Clear aperture: >85% of dimension

Beam deviation: <5'



### POLARISING BEAM SPLITTER-PBS052

Material: H-ZF3

Dimension: 5X5X5

Surface quality: 60/40

Surface flatness:  $\lambda/10$  at 633nm

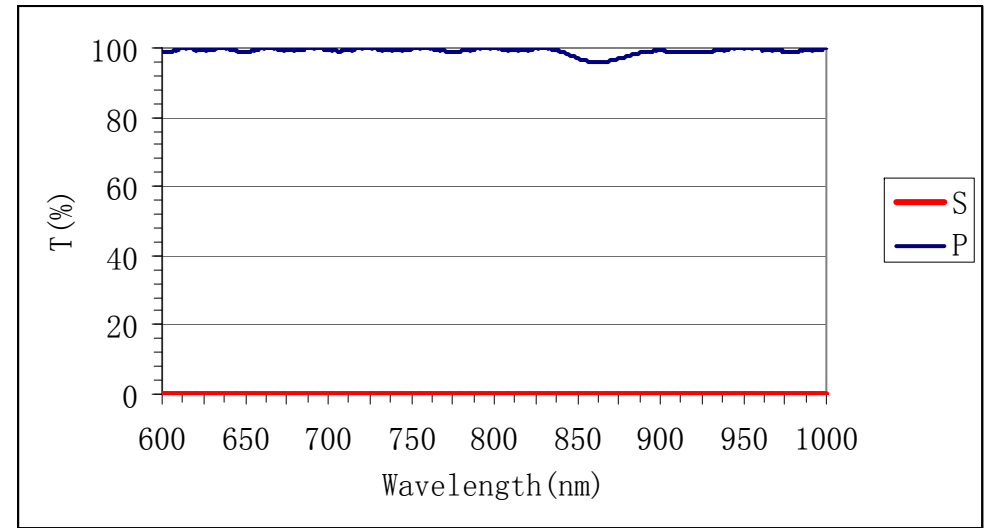
Input/Output surfaces: AR<0.5% over 600~10000nm

Hypotenuse: AOI 45 degree,  $T_p > 95\%$  and  $T_s < 0.1\%$  over 600~1000nm,

Extinction Ratio greater than 1000

Clear aperture: >85% of dimension

Beam deviation:<5'



### POLARISING BEAM SPLITTER-PBS102

Material: H-ZF3

Dimension: 10X10X10

Surface quality: 60/40

Surface flatness:  $\lambda/10$  at 633nm

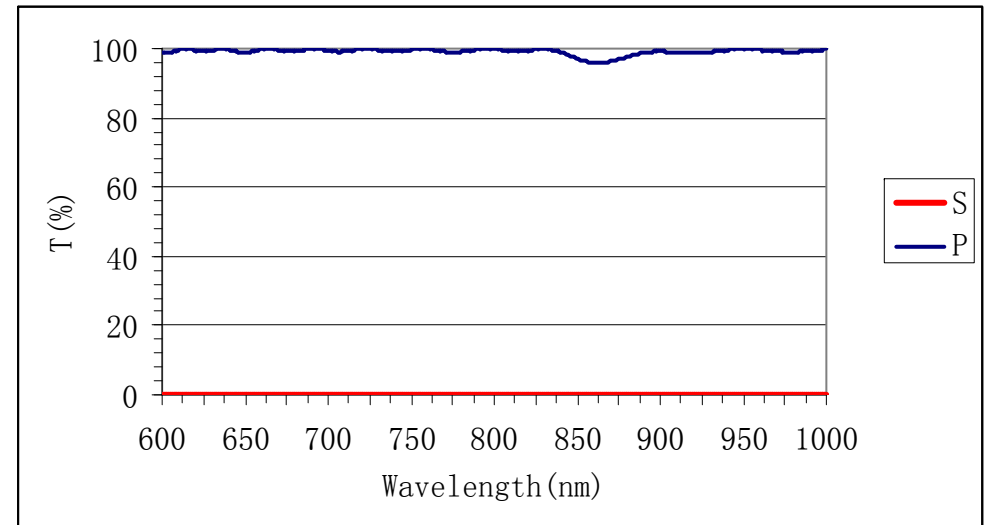
Input/Output surfaces: AR<0.5% over 600~10000nm

Hypotenuse: AOI 45 degree,  $T_p > 95\%$  and  $T_s < 0.1\%$  over 600~1000nm,

Extinction Ratio greater than 1000

Clear aperture: >85% of dimension

Beam deviation:<5'



### POLARISING BEAM SPLITTER-PBS202

Material: H-ZF3

Dimension: 20X20X20

Surface quality: 60/40

Surface flatness:  $\lambda/10$  at 633nm

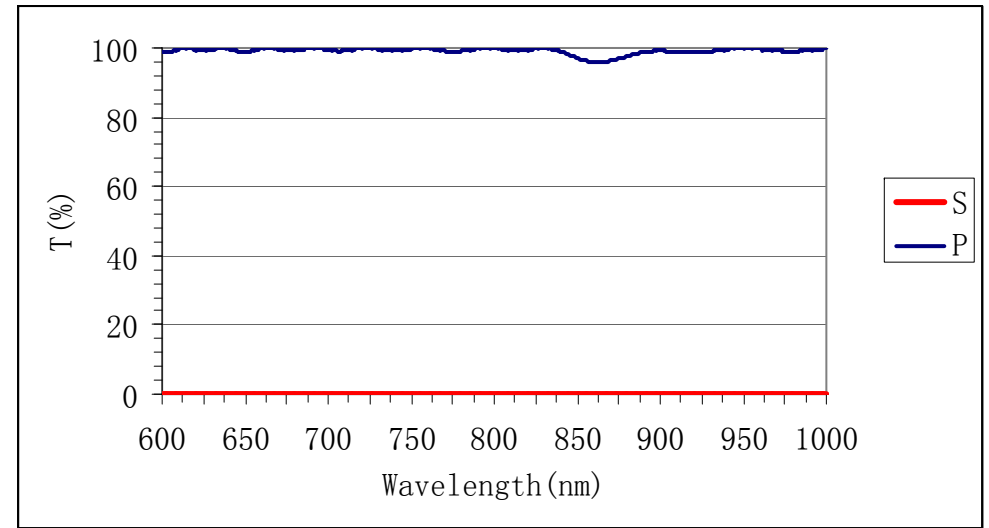
Input/Output surfaces: AR<0.5% over 600~10000nm

Hypotenuse: AOI 45 degree,  $T_p > 95\%$  and  $T_s < 0.1\%$  over 600~1000nm,

Extinction Ratio greater than 1000

Clear aperture: >85% of dimension

Beam deviation:<5'



### POLARISING BEAM SPLITTER-PBS252

Material: H-ZF3

Dimension: 25.4X25.4X25.4

Surface quality: 60/40

Surface flatness:  $\lambda/10$  at 633nm

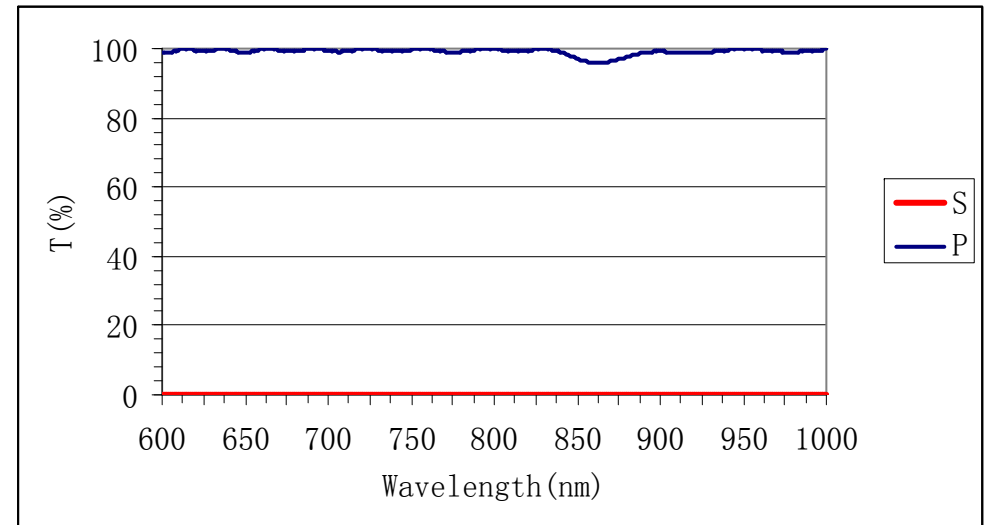
Input/Output surfaces: AR<0.5% over 600~10000nm

Hypotenuse: AOI 45 degree,  $T_p > 95\%$  and  $T_s < 0.1\%$  over 600~1000nm,

Extinction Ratio greater than 1000

Clear aperture: >85% of dimension

Beam deviation:<5'





### POLARISING BEAM SPLITTER-PBS053

Material: H-ZF3

Dimension: 5X5X5

Surface quality: 60/40

Surface flatness:  $\lambda/10$  at 633nm

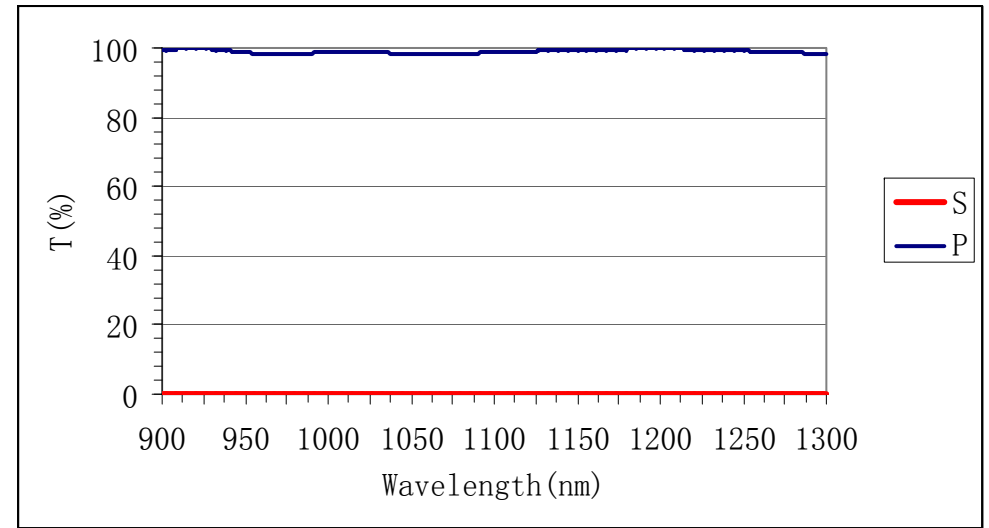
Input/Output surfaces: AR<0.5% over 900~1300nm

Hypotenuse: AOI 45 degree,  $T_p > 95\%$  and  $T_s < 0.1\%$  over 900~1300nm,

Extinction Ratio greater than 1000

Clear aperture: >85% of dimension

Beam deviation:<5'



### POLARISING BEAM SPLITTER-PBS103

Material: H-ZF3

Dimension: 10X10X10

Surface quality: 60/40

Surface flatness:  $\lambda/10$  at 633nm

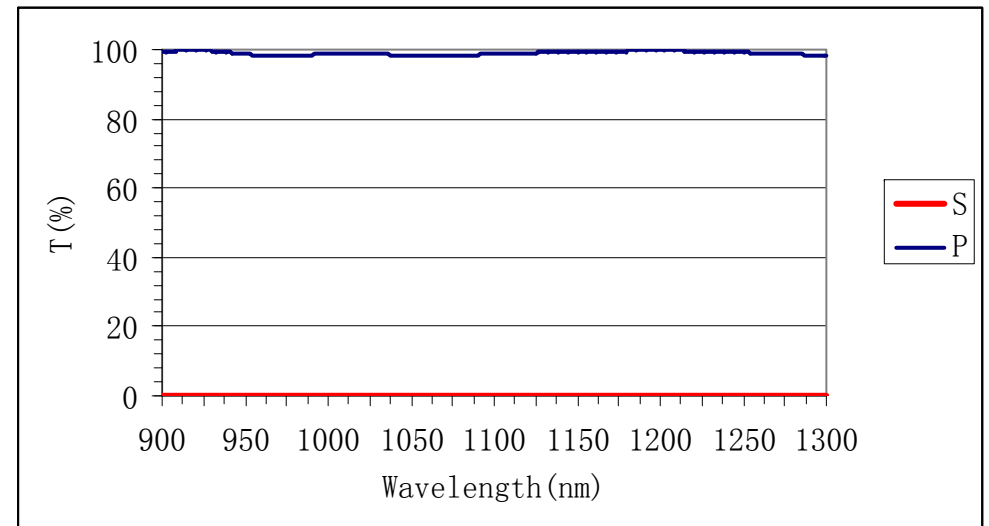
Input/Output surfaces: AR<0.5% over 900~1300nm

Hypotenuse: AOI 45 degree,  $T_p > 95\%$  and  $T_s < 0.1\%$  over 900~1300nm,

Extinction Ratio greater than 1000

Clear aperture: >85% of dimension

Beam deviation:<5'



### POLARISING BEAM SPLITTER-PBS203

Material: H-ZF3

Dimension: 20X20X20

Surface quality: 60/40

Surface flatness:  $\lambda/10$  at 633nm

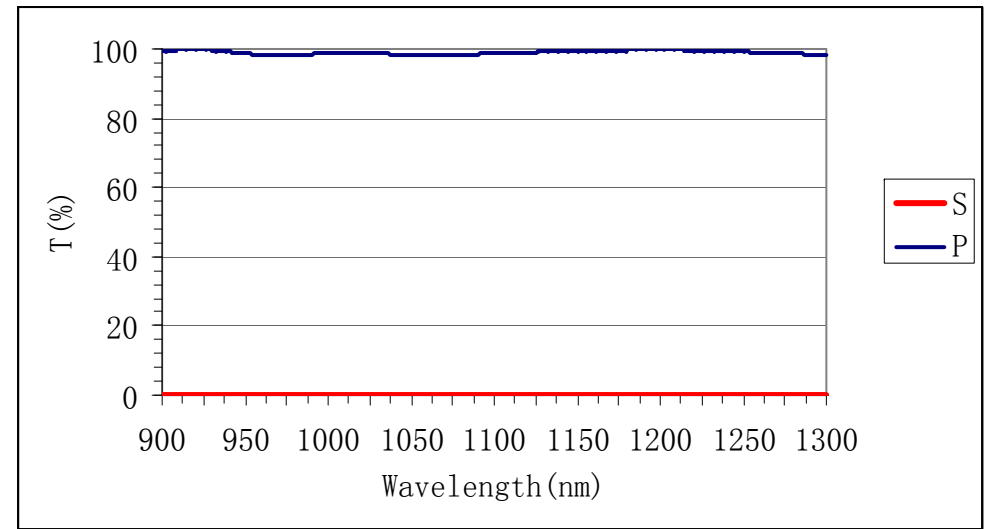
Input/Output surfaces: AR<0.5% over 900~1300nm

Hypotenuse: AOI 45 degree,  $T_p > 95\%$  and  $T_s < 0.1\%$  over 900~1300nm,

Extinction Ratio greater than 1000

Clear aperture: >85% of dimension

Beam deviation:<5'



### POLARISING BEAM SPLITTER-PBS253

Material: H-ZF3

Dimension: 25.4X25.4X25.4

Surface quality: 60/40

Surface flatness:  $\lambda/10$  at 633nm

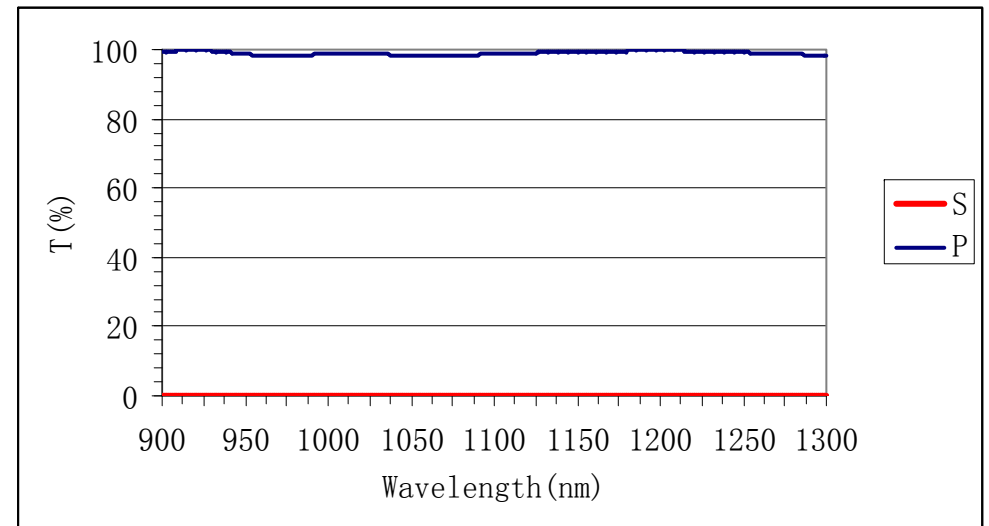
Input/Output surfaces: AR<0.5% over 900~1300nm

Hypotenuse: AOI 45 degree,  $T_p > 95\%$  and  $T_s < 0.1\%$  over 900~1300nm,

Extinction Ratio greater than 1000

Clear aperture: >85% of dimension

Beam deviation:<5'



### POLARISING BEAM SPLITTER-PBS054

Material: H-ZF3

Dimension: 5X5X5

Surface quality: 60/40

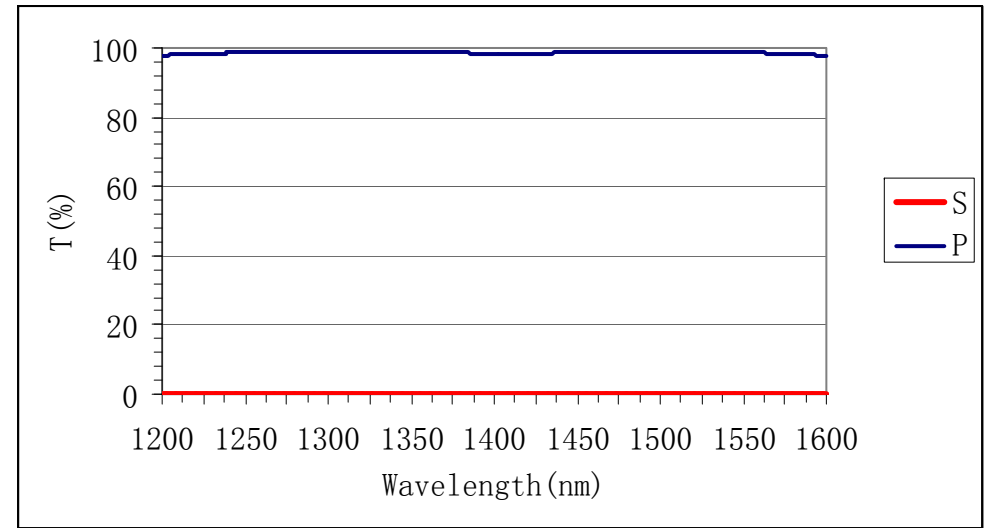
Surface flatness:  $\lambda/10$  at 633nm

Input/Output surfaces: AR<0.5% over 1200~1600nm

Hypotenuse: AOI 45 degree,  $T_p > 95\%$  and  $T_s < 0.1\%$  over 1200~1600nm, Extinction Ratio greater than 1000

Clear aperture: >85% of dimension

Beam deviation:<5'



### POLARISING BEAM SPLITTER-PBS104

Material: H-ZF3

Dimension: 10X10X10

Surface quality: 60/40

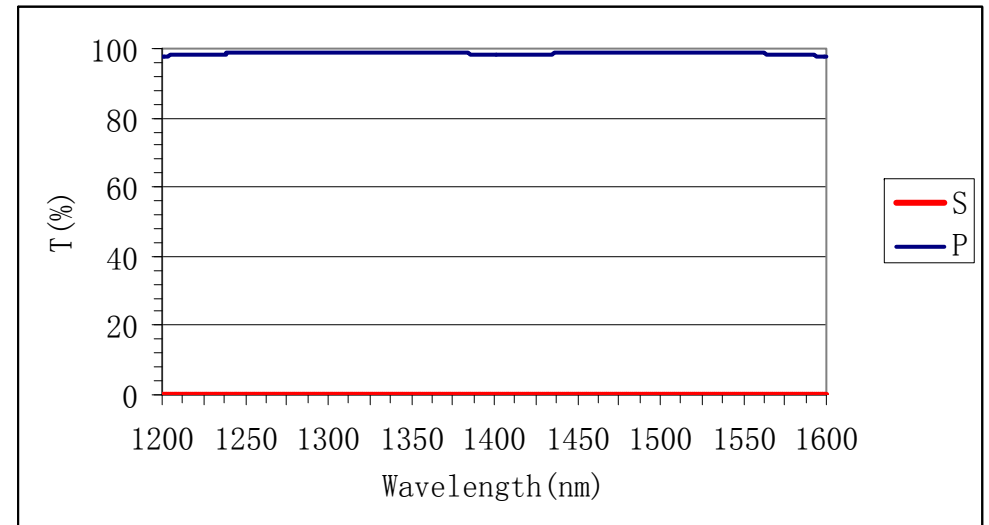
Surface flatness:  $\lambda/10$  at 633nm

Input/Output surfaces: AR<0.5% over 1200~1600nm

Hypotenuse: AOI 45 degree,  $T_p > 95\%$  and  $T_s < 0.1\%$  over 1200~1600nm, Extinction Ratio greater than 1000

Clear aperture: >85% of dimension

Beam deviation:<5'



### POLARISING BEAM SPLITTER-PBS204

Material: H-ZF3

Dimension: 20X20X20

Surface quality: 60/40

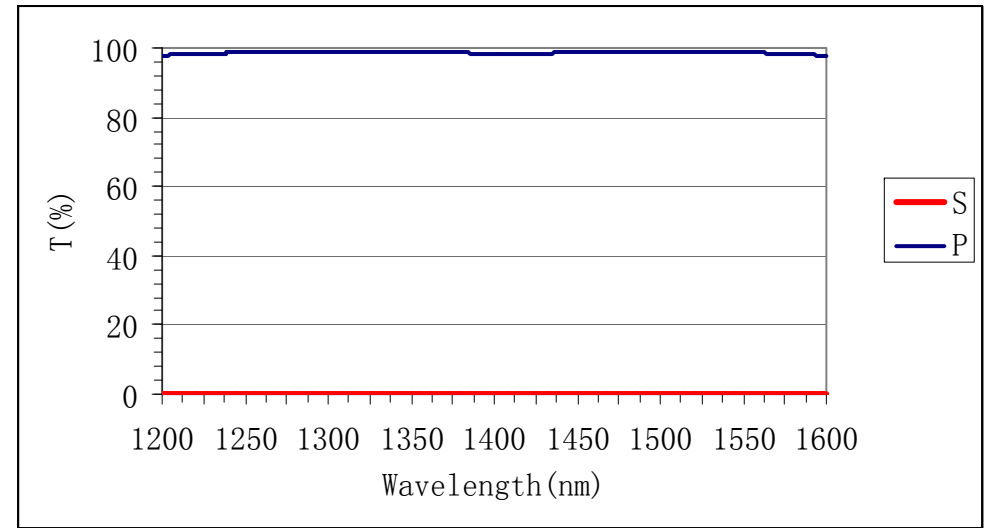
Surface flatness:  $\lambda/10$  at 633nm

Input/Output surfaces: AR<0.5% over 1200~1600nm

Hypotenuse: AOI 45 degree,  $T_p > 95\%$  and  $T_s < 0.1\%$  over 1200~1600nm, Extinction Ratio greater than 1000

Clear aperture: >85% of dimension

Beam deviation: <5'



### POLARISING BEAM SPLITTER-PBS254

Material: H-ZF3

Dimension: 25.4X25.4X25.4

Surface quality: 60/40

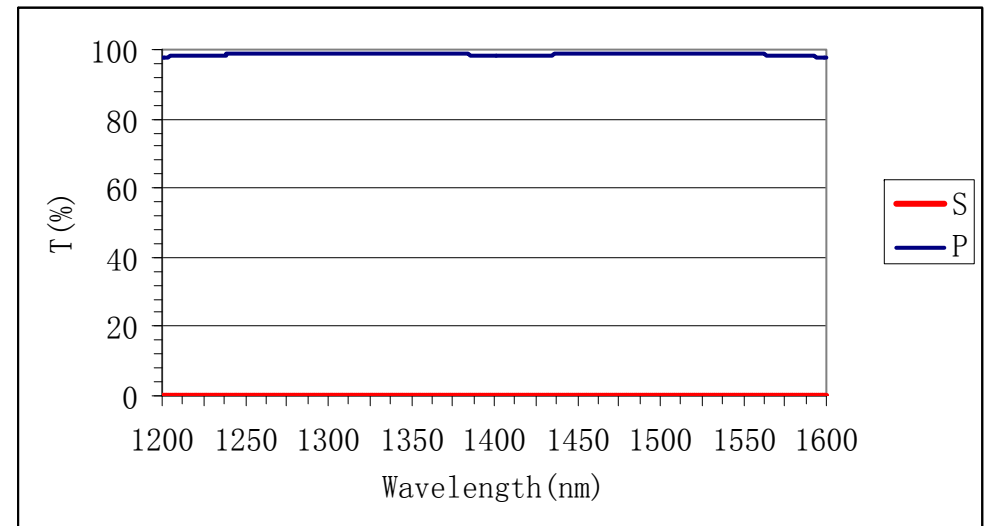
Surface flatness:  $\lambda/10$  at 633nm

Input/Output surfaces: AR<0.5% over 1200~1600nm

Hypotenuse: AOI 45 degree,  $T_p > 95\%$  and  $T_s < 0.1\%$  over 1200~1600nm, Extinction Ratio greater than 1000

Clear aperture: >85% of dimension

Beam deviation: <5'



### NON-POLARISING BEAM SPLITTER-NPBS007

Material: H-K9L

Dimension: 5X5X5

Surface quality:40/20

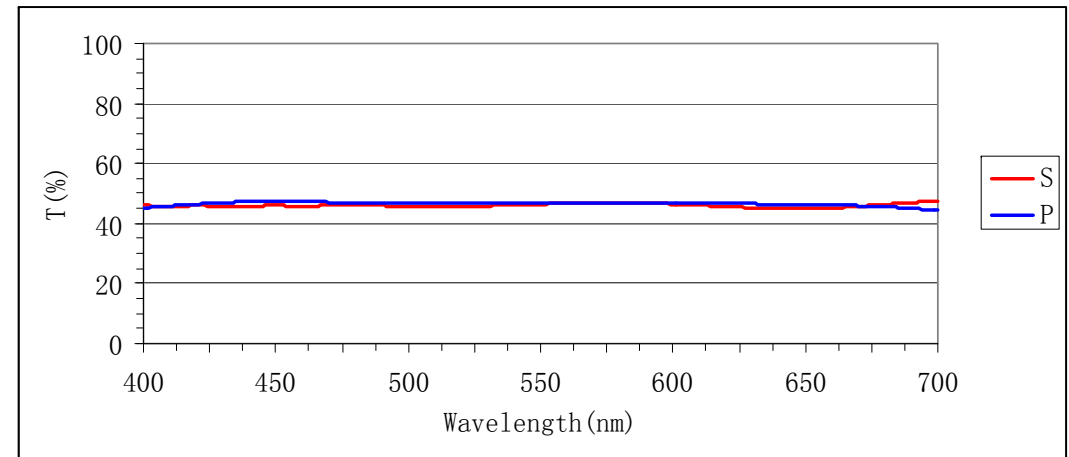
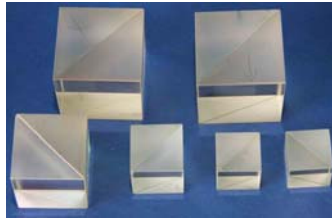
Surface flatness:  $\lambda/10$  at 633nm

Input/Output surfaces: AR<0.5% over 400~700nm

Hypotenuse: AOI 45 degree, T/R=1:1, |Tp-Ts|<15% and |Rp-Rs|<15% over 400-700nm

Clear aperture: >80% of dimension

Beam deviation:<5'



### NON-POLARISING BEAM SPLITTER-NPBS010

Material: H-K9L

Dimension: 10X10X10

Surface quality:40/20

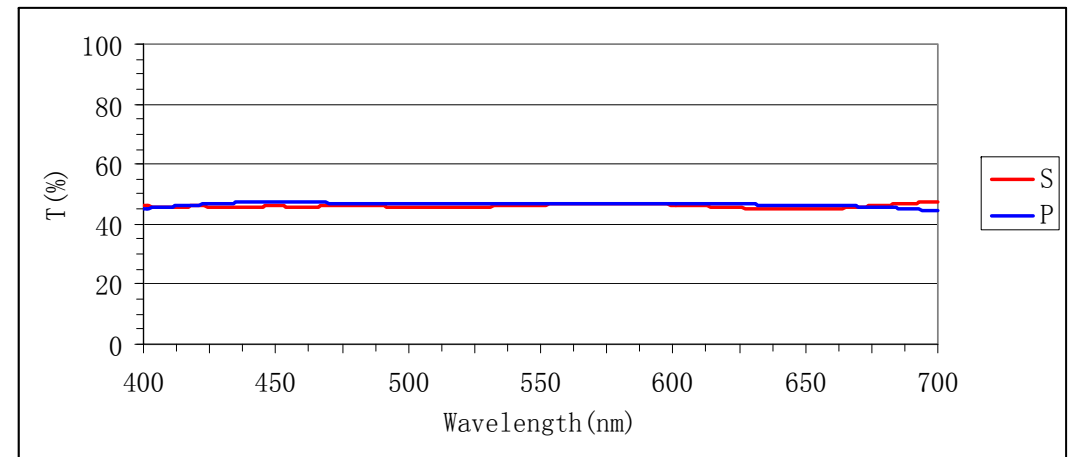
Surface flatness:  $\lambda/10$  at 633nm

Input/Output surfaces: AR<0.5% over 400~700nm

Hypotenuse: AOI 45 degree, T/R=1:1, |Tp-Ts|<15% and |Rp-Rs|<15% over 400-700nm

Clear aperture: >80% of dimension

Beam deviation:<5'



### NON-POLARISING BEAM SPLITTER-NPBS016

Material: H-K9L

Dimension: 20X20X20

Surface quality:40/20

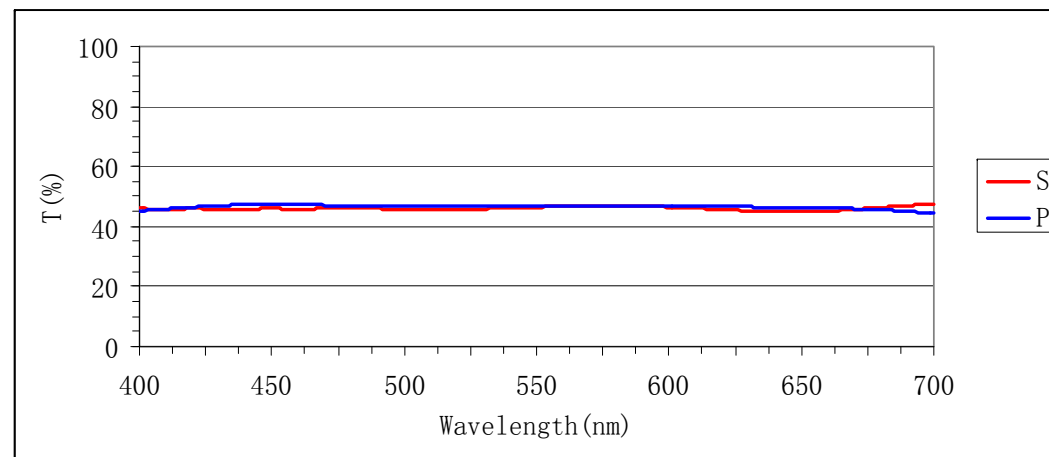
Surface flatness:  $\lambda/10$  at 633nm

Input/Output surfaces: AR<0.5% over 400~700nm

Hypotenuse: AOI 45 degree, T/R=1:1,  $|T_p-T_s|<15\%$  and  $|R_p-R_s|<15\%$  over 400-700nm

Clear aperture: >80% of dimension

Beam deviation:<5'



### NON-POLARISING BEAM SPLITTER-NPBS013

Material: H-K9L

Dimension: 25.4X25.4X25.4

Surface quality:40/20

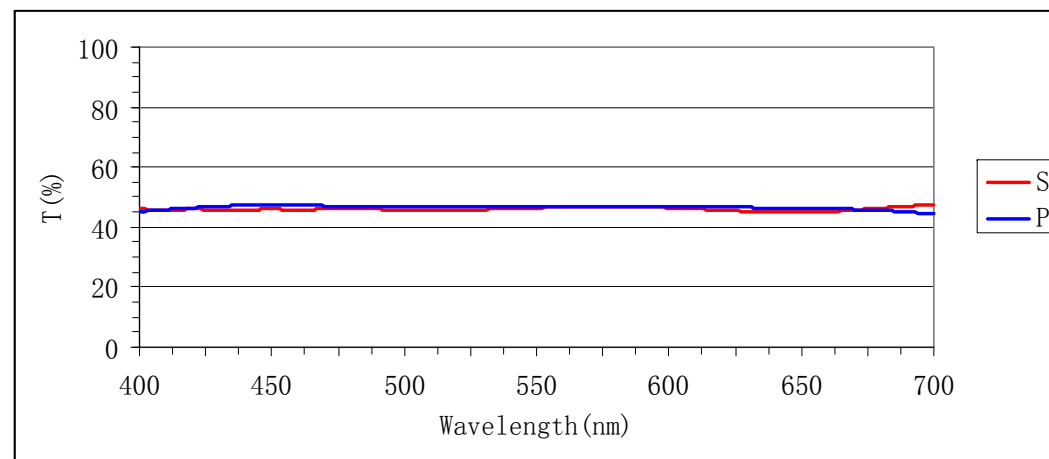
Surface flatness:  $\lambda/10$  at 633nm

Input/Output surfaces: AR<0.5% over 400~700nm

Hypotenuse: AOI 45 degree, T/R=1:1,  $|T_p-T_s|<15\%$  and  $|R_p-R_s|<15\%$  over 400-700nm

Clear aperture: >80% of dimension

Beam deviation:<5'



### NON-POLARISING BEAM SPLITTER-NPBS008

Material: H-K9L

Dimension: 5X5X5

Surface quality:40/20

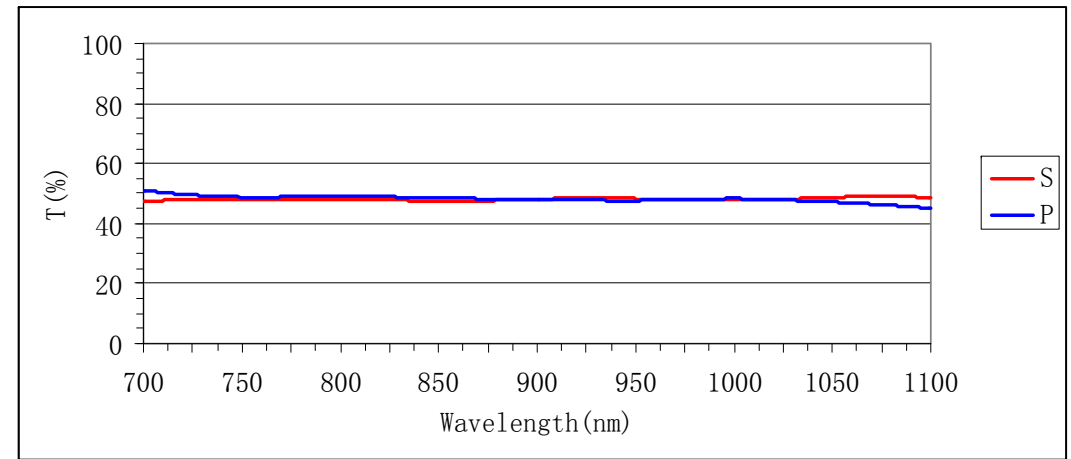
Surface flatness:  $\lambda/10$  at 633nm

Input/Output surfaces: AR<0.5% over 700~1100nm

Hypotenuse: AOI 45 degree, T/R=1:1,|Tp-Ts|<15% and |Rp-Rs|<15% over 700-1100nm

Clear aperture: >80% of dimension

Beam deviation:<5'



### NON-POLARISING BEAM SPLITTER-NPBS011

Material: H-K9L

Dimension: 10X10X10

Surface quality:40/20

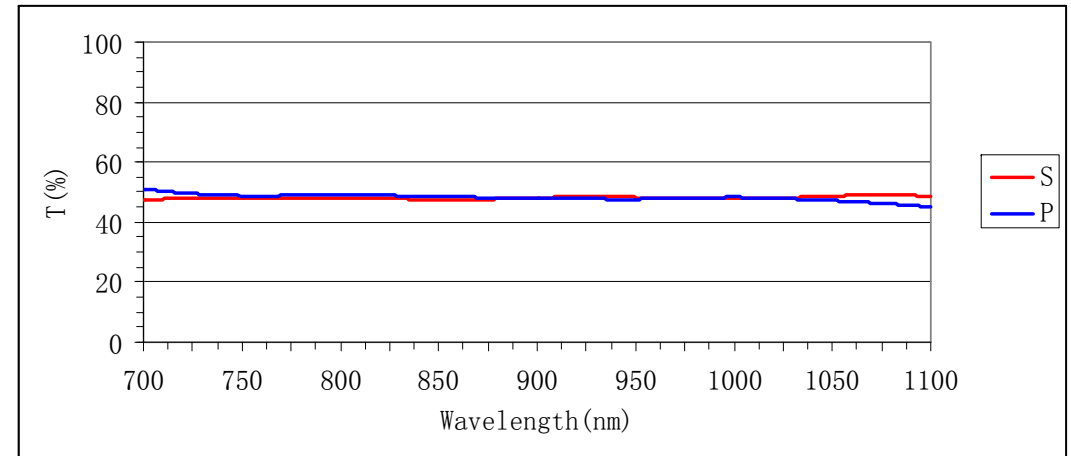
Surface flatness:  $\lambda/10$  at 633nm

Input/Output surfaces: AR<0.5% over 700~1100nm

Hypotenuse: AOI 45 degree, T/R=1:1,|Tp-Ts|<15% and |Rp-Rs|<15% over 700-1100nm

Clear aperture: >80% of dimension

Beam deviation:<5'





### NON-POLARISING BEAM SPLITTER-NPBS017

Material: H-K9L

Dimension: 20X20X20

Surface quality:40/20

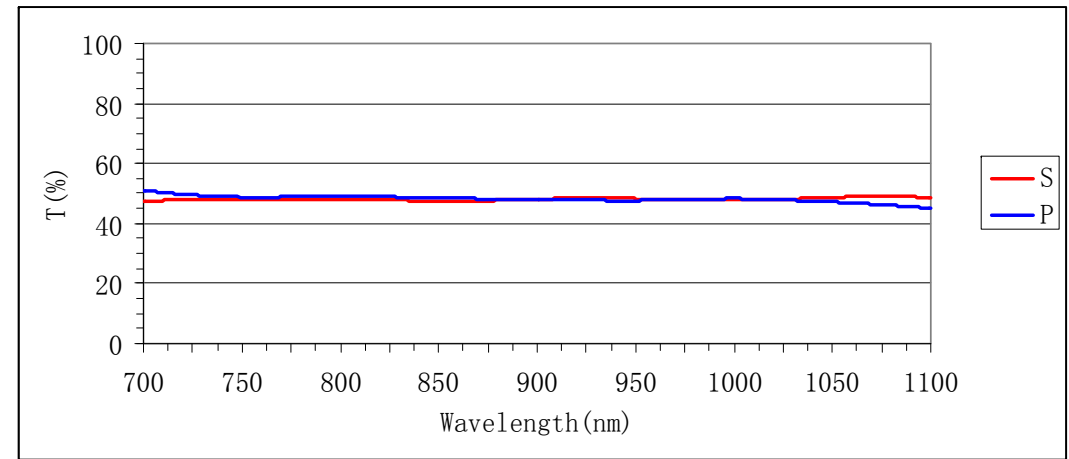
Surface flatness:  $\lambda/10$  at 633nm

Input/Output surfaces: AR<0.5% over 700~1100nm

Hypotenuse: AOI 45 degree, T/R=1:1,  $|T_p-T_s|<15\%$  and  $|R_p-R_s|<15\%$  over 700-1100nm

Clear aperture: >80% of dimension

Beam deviation:<5'



### NON-POLARISING BEAM SPLITTER-NPBS014

Material: H-K9L

Dimension: 25.4X25.4X25.4

Surface quality:40/20

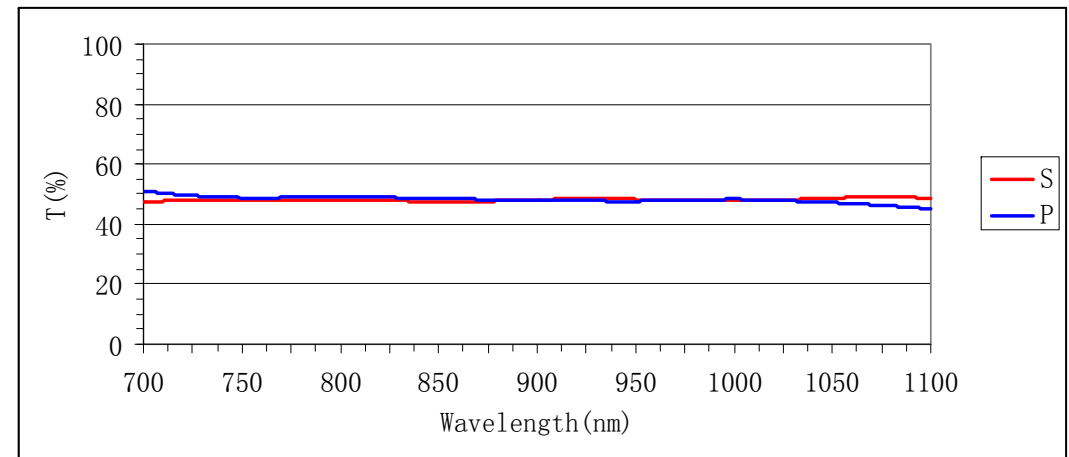
Surface flatness:  $\lambda/10$  at 633nm

Input/Output surfaces: AR<0.5% over 700~1100nm

Hypotenuse: AOI 45 degree, T/R=1:1,  $|T_p-T_s|<15\%$  and  $|R_p-R_s|<15\%$  over 700-1100nm

Clear aperture: >80% of dimension

Beam deviation:<5'



### NON-POLARISING BEAM SPLITTER-NPBS009

Material: H-K9L

Dimension: 5X5X5

Surface quality:40/20

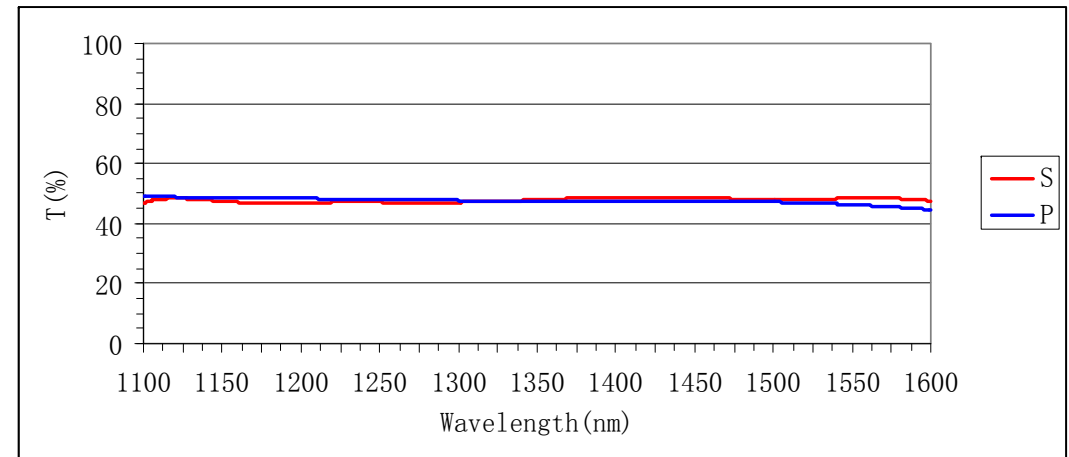
Surface flatness:  $\lambda/10$  at 633nm

Input/Output surfaces: AR<0.5% over 1100~1600nm

Hypotenuse: AOI 45 degree, T/R=1:1,  $|T_p-T_s|<15\%$  and  $|R_p-R_s|<15\%$  over 1100-1600nm

Clear aperture: >80% of dimension

Beam deviation:<5'



### NON-POLARISING BEAM SPLITTER-NPBS012

Material: H-K9L

Dimension: 10X10X10

Surface quality:40/20

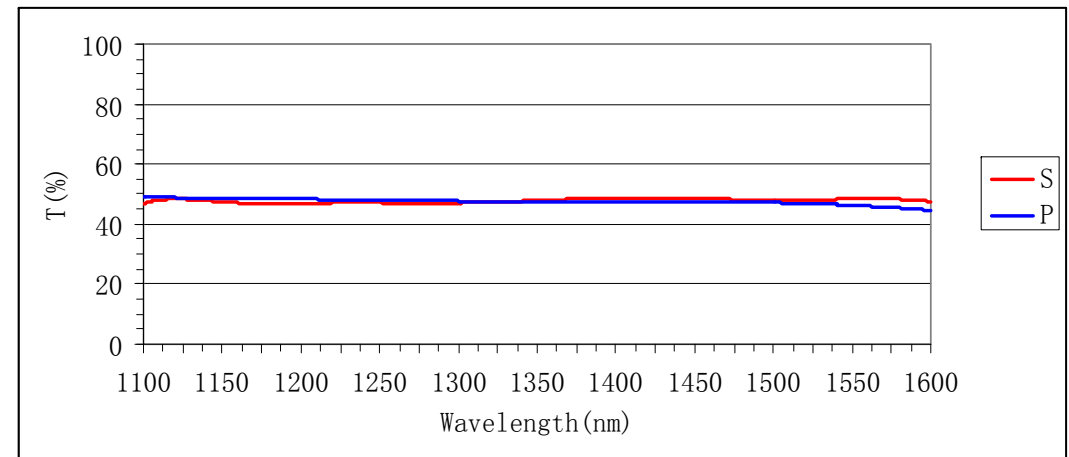
Surface flatness:  $\lambda/10$  at 633nm

Input/Output surfaces: AR<0.5% over 1100~1600nm

Hypotenuse: AOI 45 degree, T/R=1:1,  $|T_p-T_s|<15\%$  and  $|R_p-R_s|<15\%$  over 1100-1600nm

Clear aperture: >80% of dimension

Beam deviation:<5'



### NON-POLARISING BEAM SPLITTER-NPBS018

Material: H-K9L

Dimension: 20X20X20

Surface quality:40/20

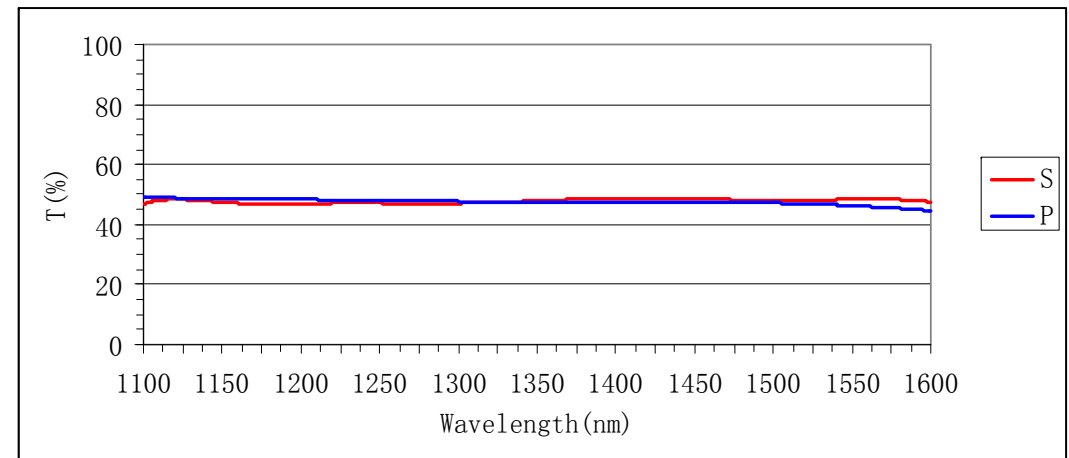
Surface flatness:  $\lambda/10$  at 633nm

Input/Output surfaces: AR<0.5% over 1100~1600nm

Hypotenuse: AOI 45 degree, T/R=1:1,  $|T_p-T_s|<15\%$  and  $|R_p-R_s|<15\%$  over 1100-1600nm

Clear aperture: >80% of dimension

Beam deviation:<5'



### NON-POLARISING BEAM SPLITTER-NPBS015

Material: H-K9L

Dimension: 25.4X25.4X25.4

Surface quality:40/20

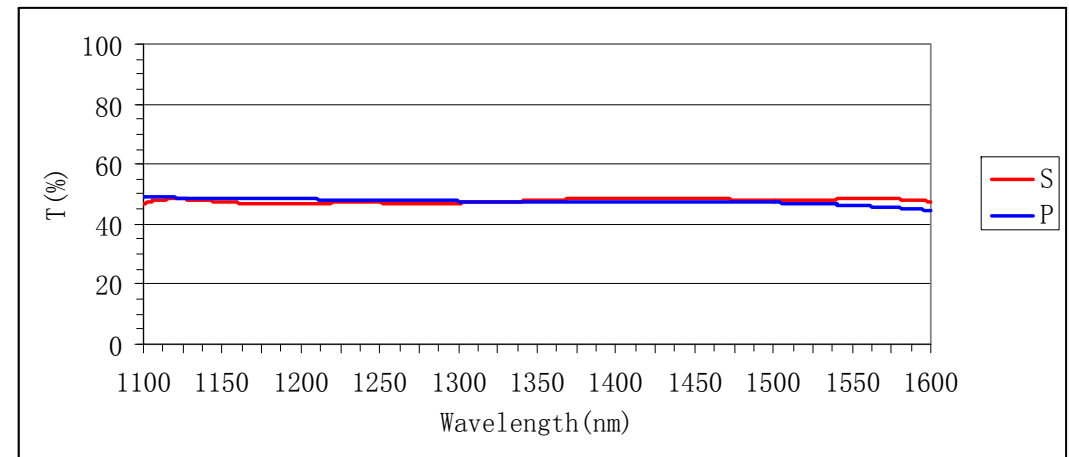
Surface flatness:  $\lambda/10$  at 633nm

Input/Output surfaces: AR<0.5% over 1100~1600nm

Hypotenuse: AOI 45 degree, T/R=1:1,  $|T_p-T_s|<15\%$  and  $|R_p-R_s|<15\%$  over 1100-1600nm

Clear aperture: >80% of dimension

Beam deviation:<5'



## NON-POLARISING BEAM SPLITTER-NPBS153

Material: H-K9L

Dimension: 15X15X15

Surface quality:40/20

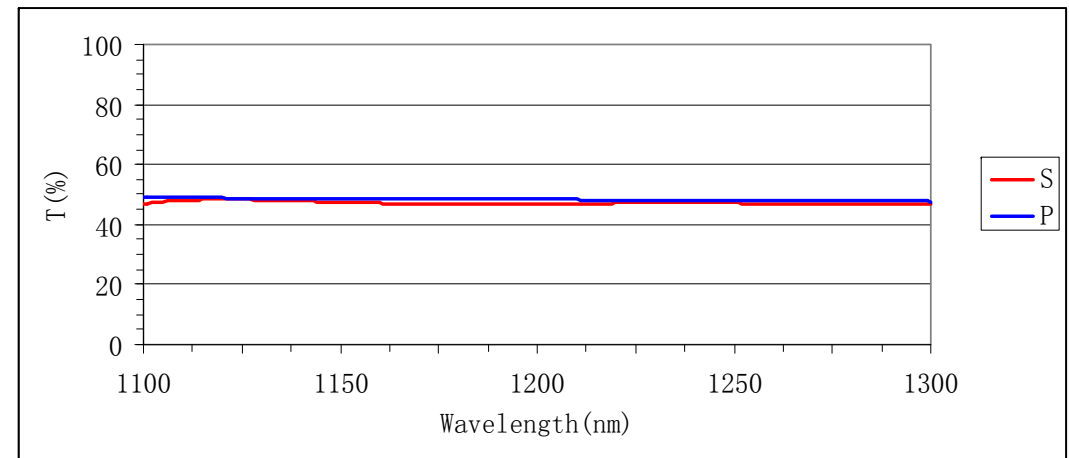
Surface flatness:  $\lambda/10$  at 633nm

Input/Output surfaces: AR<0.5% over 1100~1300nm

Hypotenuse: AOI 45 degree, T/R=1:1,  $|T_p-T_s|<7%$  and  $|R_p-R_s|<7%$  over 1100-1300nm

Clear aperture: >80% of dimension

Beam deviation:<5'



## LONG PASS FILTER FOR IPL PHOTOREJUVENATION

Material: H-K9L, Sapphire, Fused Silica

Dimension:50X47X15(light guide), 50X12X0.7(plate)

Surface quality:60/40

Transmission: 420-1200nm, 530-1200nm, 560-1200nm, 640-1200nm,

etc.

T<0.1% at rejection band, and T>90% at pass band

Feature: high damage threshold

